

Amendments in the specification:

1) Please replace the paragraph beginning on line 16 of page 1 with the following paragraph:

The present application cross references the concurrently filed and commonly owned US Patent Application 10/723,298 titled "Compact Wafer Handling System With Single Axis Robotic Arm And Prealigner-Cassette Elevator" by Marc Aho and Daniel Tran, which is hereby incorporated by reference.

2) Please replace the paragraph beginning on line 9 of page 2 with the following paragraph:

A pinlifter assembly needs to be simple and compact while providing a smooth and balanced motion of each pin contacting the wafer. In addition, the pinlifter assembly needs to be designed around other features affiliated with the positioning and holding of the wafer. Such features may include vacuum systems for holding the wafer onto the wafer holding face and precision motion systems for moving the chuck together with the wafer. Such a motion system may be for example an X-Y stage or a rotary stage. All these limiting aspects need to be accounted for by the design of the pinlifter assembly. At the same time, the pinlifter assembly is desirably compact and highly integrated in the wafer chuck. The present invention addresses ~~this~~ these needs

3) Please replace the paragraph beginning on line 29 of page 2 with the following paragraph:

The combination of wedge guides and pin actuator takes advantage of the relatively large lateral dimensions of the wafer chuck to move the pin actuator between end positions that are in a distance multiple of the pin lifters movement. Due to the wedge angle, the ~~actuators~~ actuator's comparatively large scale movement is transformed to ~~in~~ a highly precise, smooth and balanced movement of the pin lifters.

4) Please replace the paragraph beginning on line 2 of page 5 with the following paragraph:

The chuck body **51** further features at least three but preferably four pin channels **518** preferably concentrically arranged with respect to a center axis **CA** of the chuck **5**. The pin channels **518** are substantially perpendicular to the wafer holding face **510** and are correspondingly shaped to pinlifters **53** (see **Figs. 5, 7**). The pinlifters **53** are slidably ~~slide-ably~~ embedded in the pin channels **518** for lifting and lowering a wafer with respect to the wafer holding face **510**. Each pinlifter **53** has a top face **531** and a bottom face **532** (see **Fig. 5**). In **Fig. 2**, the pinlifters **53** are shown in a bottom position, in which the top faces **531** are below the holding face **510**.

5) Please replace the paragraph beginning on line 12 of page 6 with the following paragraph:

The pin actuator **55** has sliding features **552** correspondingly shaped to the wedge guides **542** and is slidably ~~slide-ably~~ guided by said wedge guides **542**. The sliding

features **552** may be configured in any well known fashion such as ~~snuggly~~ snugly fitting profiles, line contacting glide pins or rollers.

6) Please replace the paragraph beginning on line 24 of page 6 with the following paragraph:

The stepper motor is particularly suitable as a ~~motoring device~~ to be embedded inside a shallow cavity since it may be readily and commercially available in configurations with low extension along its rotation axis **RA**. In such case, the stepper motor may be embedded in the cavity with its rotation axis **RA** substantially perpendicular the holding face **510**.

7) Please replace the paragraph beginning on line 26 of page 7 with the following paragraph:

The top position preferably corresponds to a loading level at which the wafer may be accessed from beneath by a robotic arm for further transfer away from the chuck **5**. For that purpose, the pinlifters **53** may be lowered again once the robotic arm is in loading position such that the weight of the wafer is transferred from the top faces **531** onto the robotic arm. Likewise and in an opposite sequence of steps, the pinlifters **53** may be moved into their top position while a wafer is held in position above the wafer holding face **510**. The pinlifters **53** may be moved by ~~locically and/or~~ computerized controlled powering the actuator drive **56** in a well known fashion. Within a wafer testing device **1** such as described in the concurrently filed and cross referenced application 10/723,298 titled

"Compact Wafer Handling System With Single Axis Robotic Arm And Prealigner-Cassette Elevator" the pinlifter **53** movement may be defined as a movement along dual positioning axes **DP**. In such testing device **1**, the controlled powering may be accomplished by a control system of the testing device **1**.